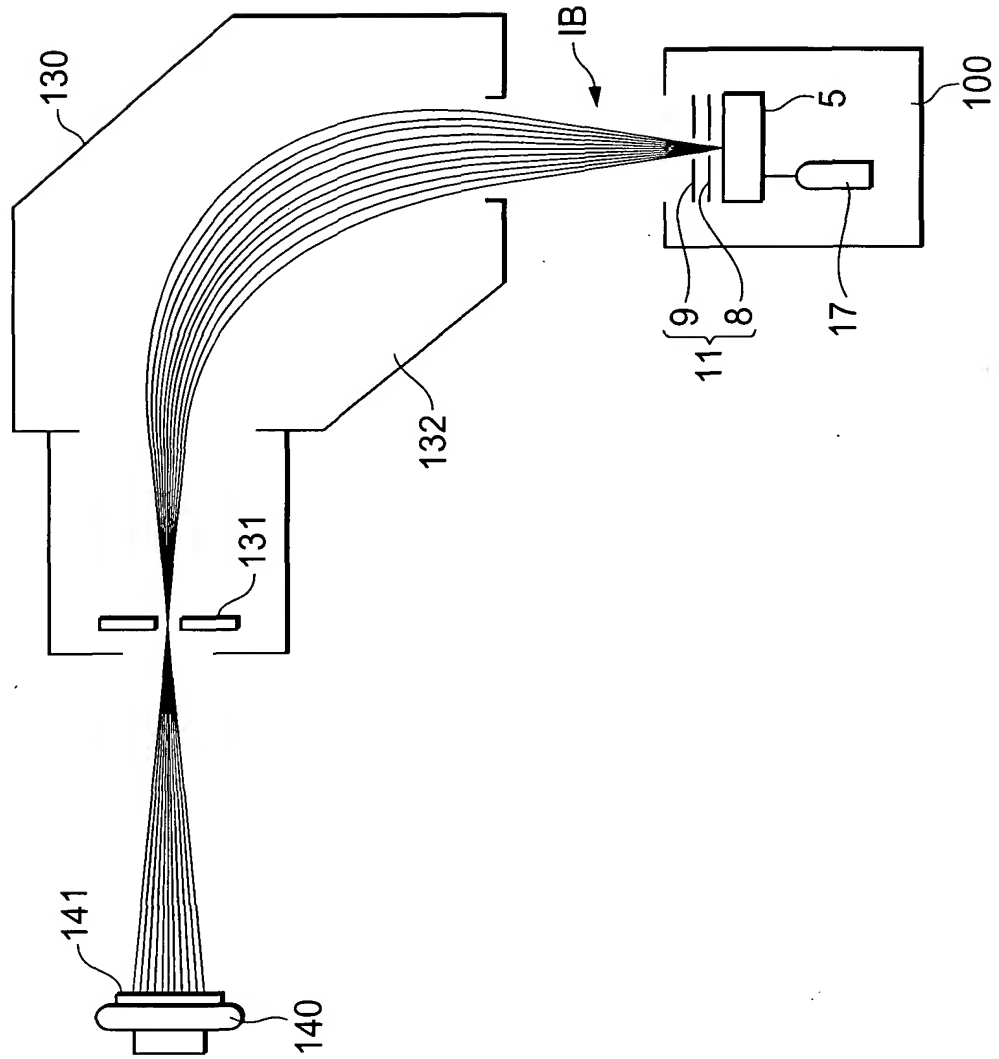
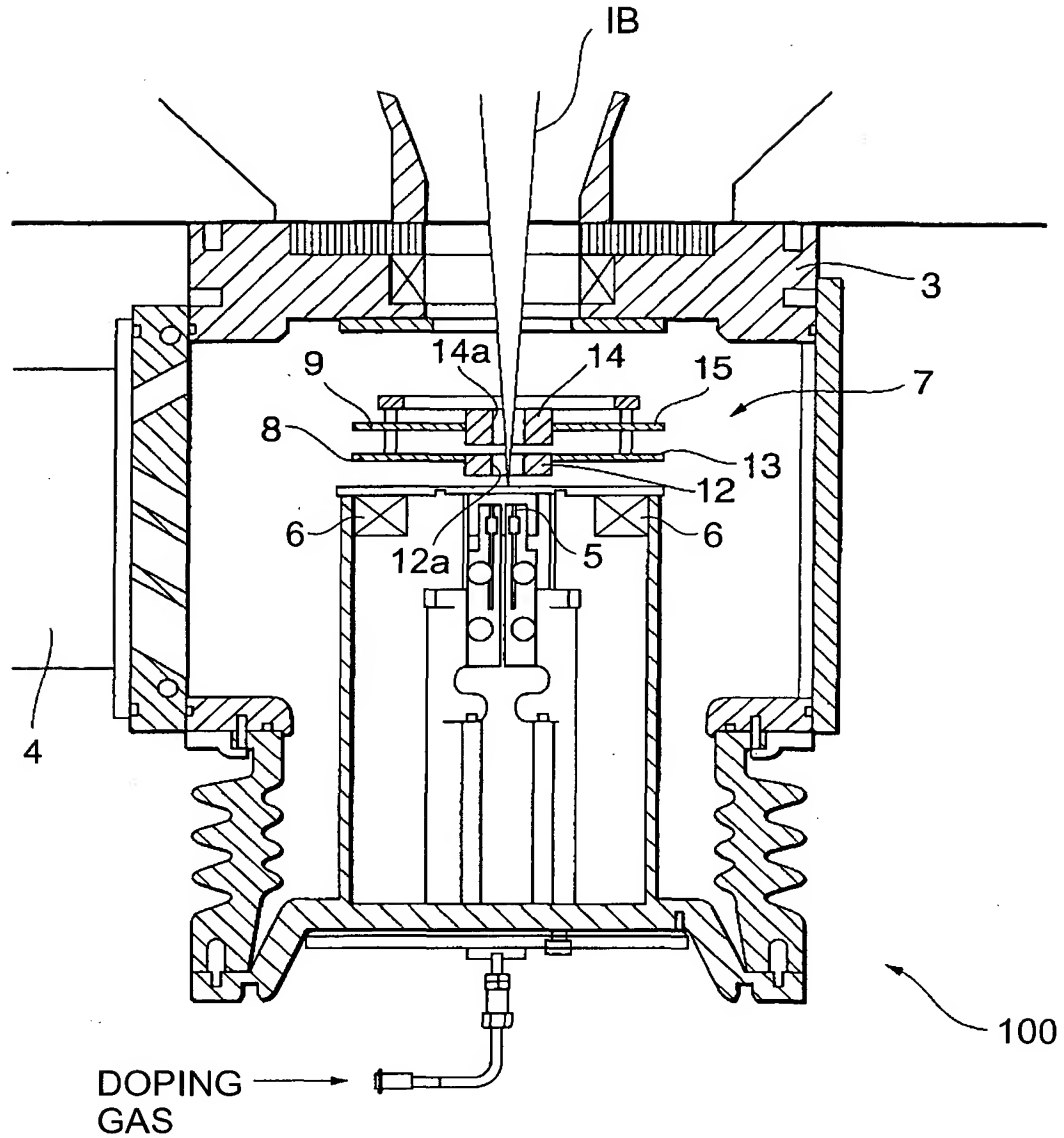


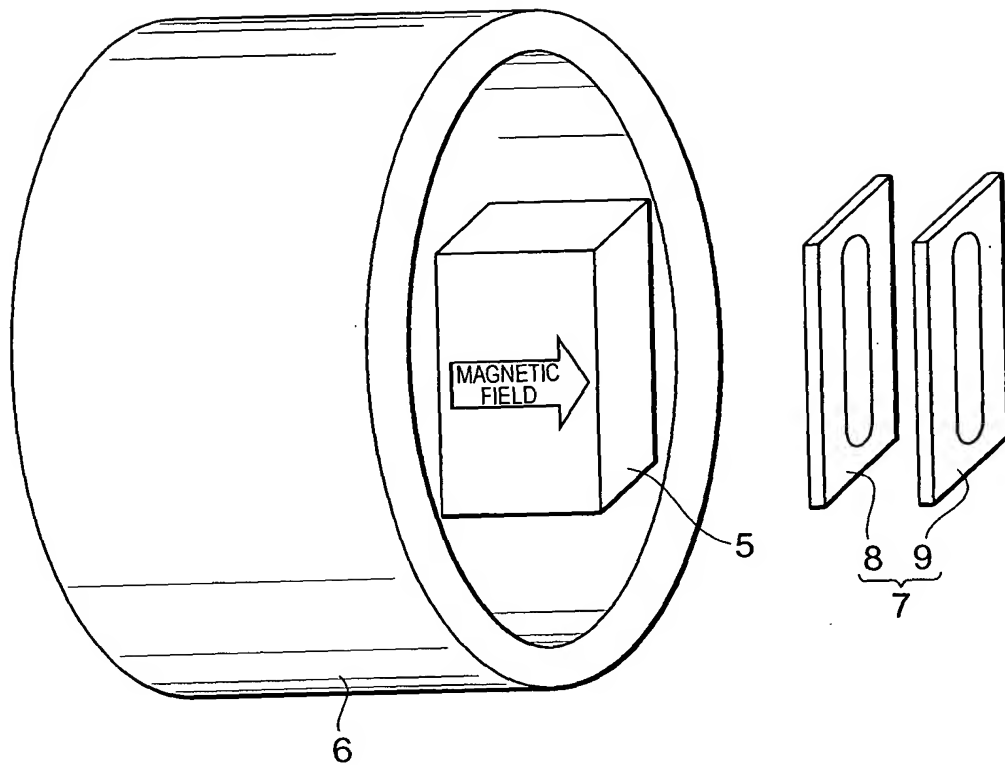
**Fig.1**



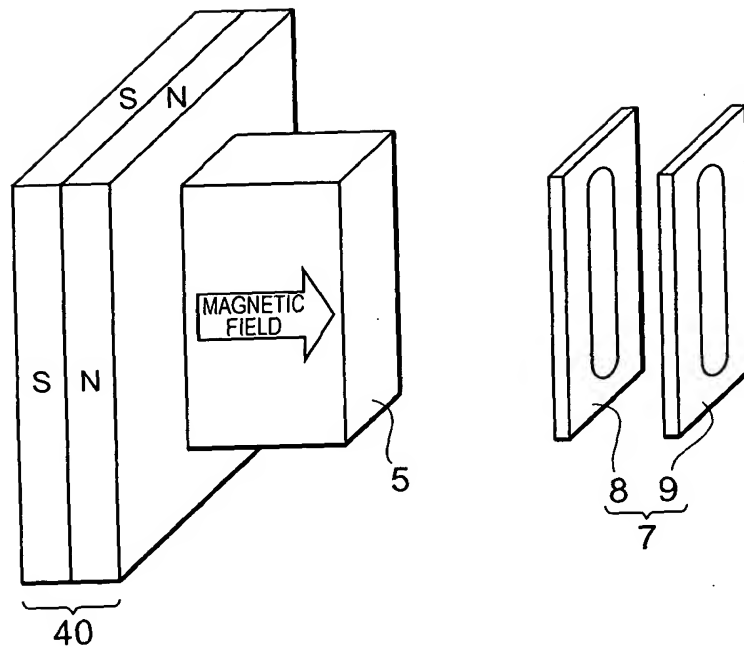
**Fig.2**

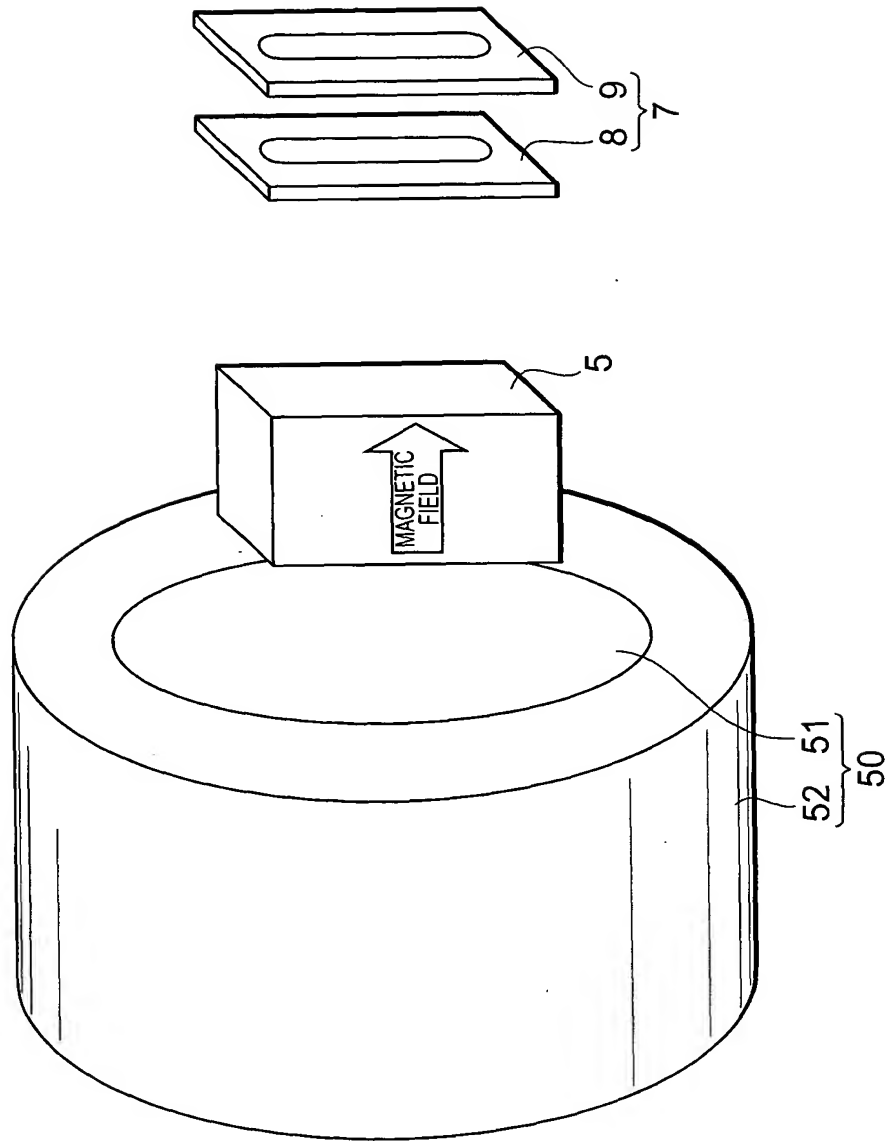
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| FILED:           | HEREWITH  |            |         |
| APPLICANT:       | APPLIED MATERIALS, INC.   |            |         |
| TITLE:           | ION IMPLANTATION METHOD, SOI WAFER MANUFACTURING METHOD AND ION IMPLANTATION SYSTEM |            |         |
| INVENTOR:        | ITO, ET AL.   |            |         |

**Fig.3**



**Fig.4**

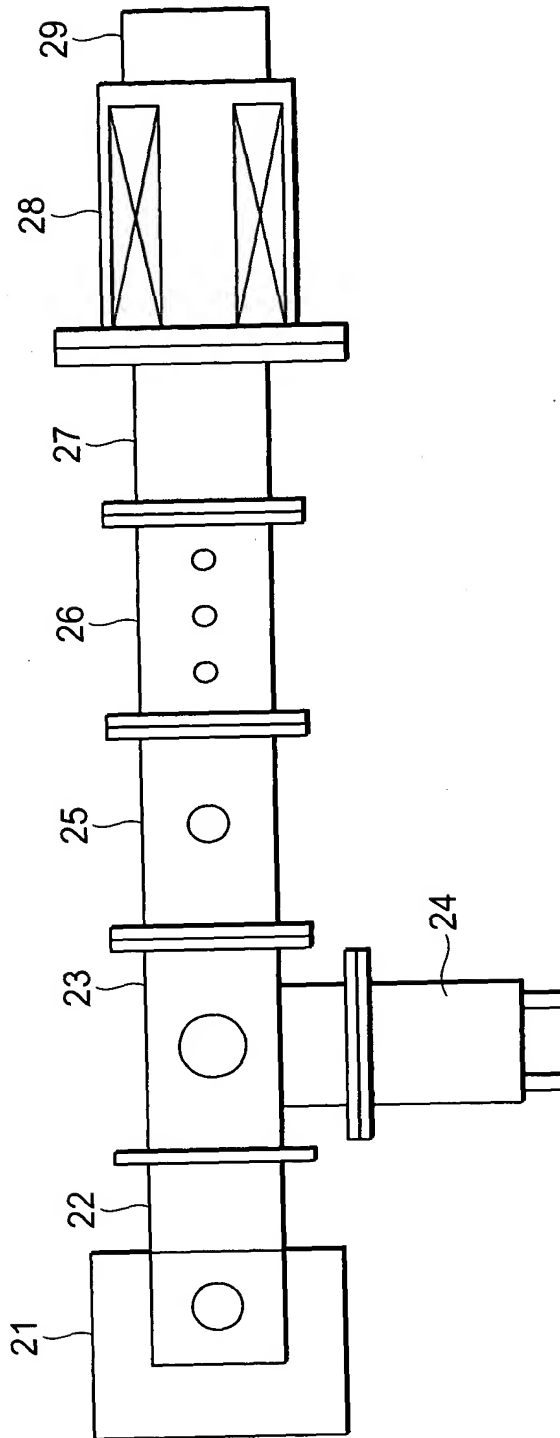




**Fig. 5**

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**Fig.6**



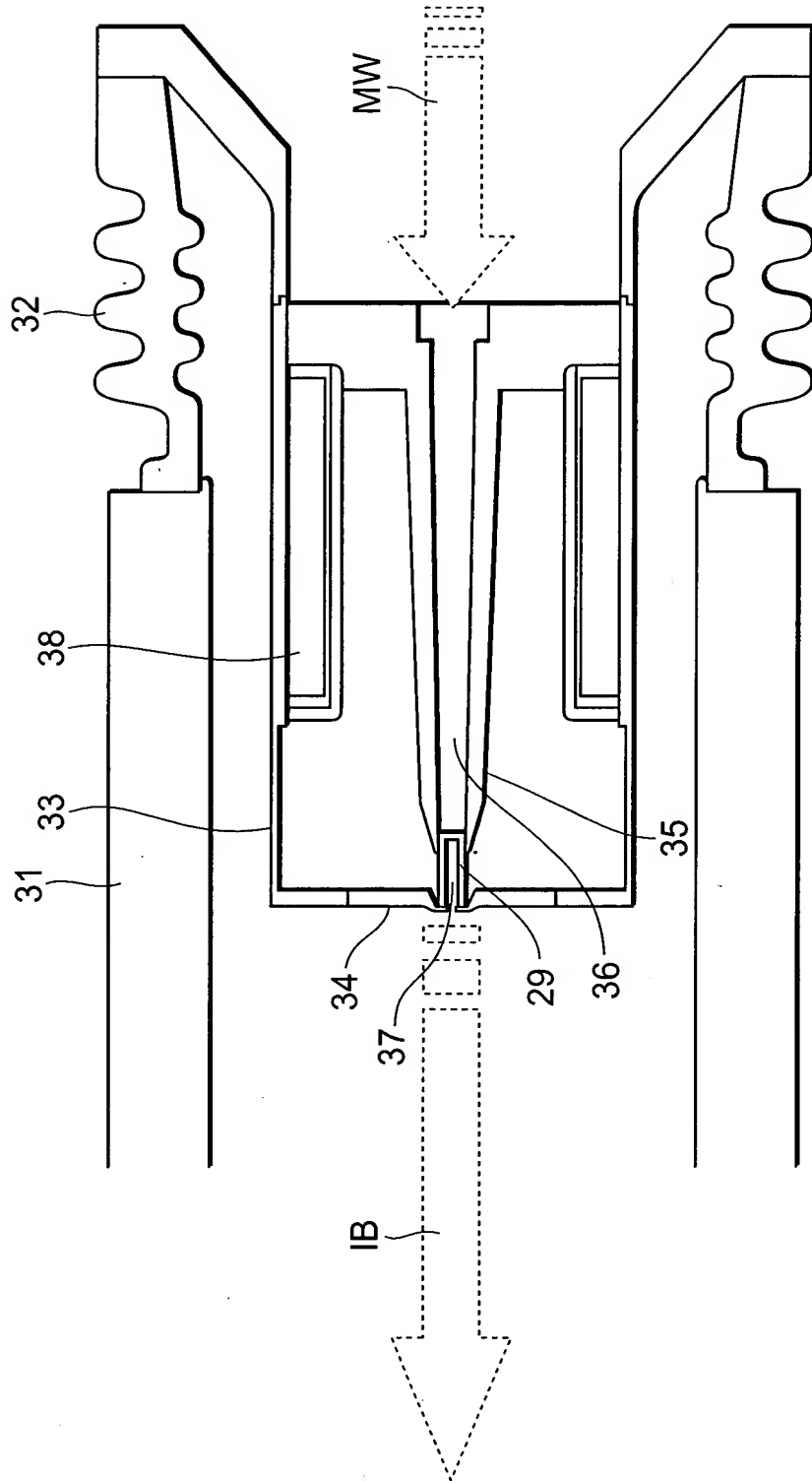
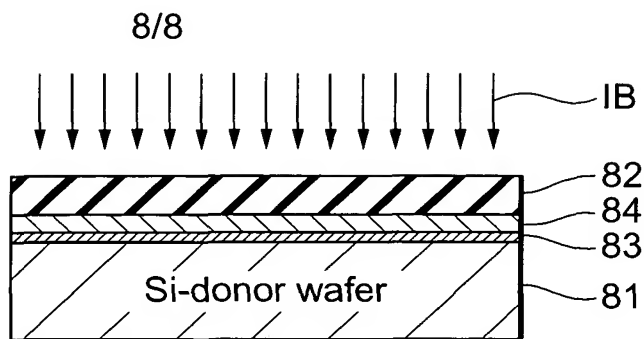


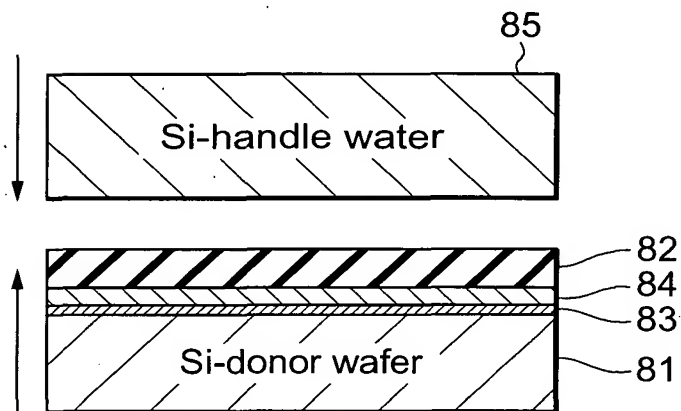
Fig. 7

|                  |   |            |         |
|------------------|---|------------|---------|
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| APPLICANT:       | APPLIED MATERIALS, INC.   |            |         |
| TITLE:           | ION IMPLANTATION METHOD, SOI WAFER MANUFACTURING METHOD AND ION IMPLANTATION SYSTEM |            |         |
| INVENTOR:        | ITO, ET AL.   |            |         |

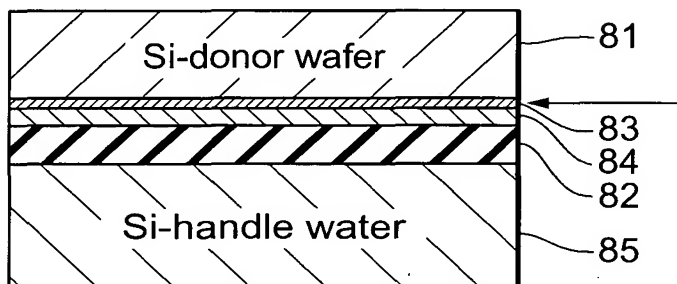
**Fig.8A**



**Fig.8B**



**Fig.8C**



**Fig.8D**

